

STNG USPAT2 - update 10/02'  
STN Columbus

(FILE 'HOME' ENTERED AT 15:40:20 ON 19 OCT 2002)

FILE 'USPAT2' ENTERED AT 15:40:47 ON 19 OCT 2002

L1 2618 S RESIST# OR PHOTORESIST#  
L2 121 S HARD(3A)MASK?  
L3 16726 S ETCH? OR PATTERN? OR REMOVE? OR PATTERN?  
L4 3393 S PLASMA? OR SPUTTER? OR CORONA? OR RIE OR MRIE OR MERIE OR GLO  
L5 L4 S L1(P);L2(P);L3(P);L4  
L6 6114 S INERT(3A)GAS? OR N2 OR HE OR AR OR KR OR Xe OR N(3W)2  
L7 4042 S ARGON OR HELIUM OR XENON OR NITROGEN OR NEON  
L8 5 S L5(P); L6 (P); L7)  
L9 4058 S C(3W)2 OR O(3W); OR OXYGEN? OR O2 OR O3  
L10 5 S L8(P);L9 OR OZONE?  
L11 3 S L8 (P); O2 OR CO2 OR COXIDE OR SO OR SO2 OR ClO OR ClO2 OR NO  
L12 5 S L10 OR L11  
L13 1 S L12(P) (CF4 OR C2F6 OR C3F8 OR SF6 OR CHF3 OR CH2F2 OR CH3F  
L14 5 S L12 OR L13  
L15 1521 S BILEVEL OR BILAYER OR MULTILAYER OR MULTI(W)LEVEL? OR MULTI(W  
L16 7 S L1(P);L12(P);L13(P); L4 (P); L6 OR L7)  
L17 5 S L10 NOT L1  
L18 444 S (RESIST# OR PHOTORESIST#)/CLM  
L19 185 S (HARD(3A)MASK? OR FILEVEL OR BILAYER OR MULTILAYER OR MULTILE  
L20 0 S MULTI/CLM  
L21 692 S MULTI/CLM  
L22 4940 S (ETCH? OR PATTERN? OR PATTERN? OR REMOVE?)/CLM  
L23 656 S (PLASMA? OR SPUTTER? OR CORONA? OR RIE OR MRIE OR MERIE OR GL  
L24 46 S (FEATURE?(3A)ION), CLM  
L25 6 S L18 AND (L19 OR L20) AND L21 AND (L23 OR L24)  
L26 1051 S (INERT(3A)GAS? OR N2 OR HE OR AR OR KR OR Xe OR N(3W)2 )/CLM  
L27 833 S (ARGON OR HELIUM OR XENON OR NITROGEN OR NEON)/CLM  
L28 3 S L25 AND (L26 OR L27)  
L29 3 S L28 NOT L17  
L30 1 S L28 NOT L8

STN 8 Cas Japio Inspen - Update 10/02/11

(FILE 'HOME' ENTERED AT 18:37:01 ON 18 OCT 2002)

FILE 'CA' ENTERED AT 18:37:11 ON 18 OCT 2002

L1 59003 S RESIST OR PHOTORESIST  
L2 902 S HARD(3A)MASK?  
L3 1578103 S ETCH? OR PATERN? OR PATTERN? OR REMOV?  
L4 804528 S PLASMA# OR SPUTTER? OR CORONA OR RIE OR MRIE OR MERIE OR  
GLOW  
L5 16640 S LOW(3W)(K OR DIELECTRIC?)  
L6 1035740 S N2 OR NITROGEN? OR INERT(3A)GAS? OR AR OR KR OR XE OR HE  
OR A  
L7 297991 S N(3W)2  
L8 164 S L1 AND L2 AND L3 AND L4  
L9 58 S L8 AND (L6 OR L7)  
L10 6 S L5 AND L9  
L11 32 S L9 AND POLY?  
L12 33 S L10 OR L11  
L13 5 S L9 AND (POLYI? OR POLYA?)  
L14 16 S L9 AND POLYM?  
L15 21 S L10 OR L13 OR L14

FILE 'JAPIO' ENTERED AT 18:42:00 ON 18 OCT 2002

L16 0 S L15

FILE 'INSPEC' ENTERED AT 18:42:26 ON 18 OCT 2002

L17 3 S L15

West 8 WPI, USPT, PGPB, TDBD - update  
**WEST Search History**  
 10/02/

DATE: Friday, October 18, 2002

**Set Name Query**  
 side by side

**Hit Count Set Name**  
 result set

*DB TDBD; PLUR YES; OP OR*

L20	L19 and l18 and l17 and l16	0	L20
L19	n2 or nitrogen or ar or argon or he or helium or ne or neon or kr or krypton or inert near3 gas\$ or xe or xenon	3893	L19
L18	etch\$ or patern\$ or pattern\$ or remov\$	22249	L18
L17	hard near3 mask?	1	L17
L16	resist or photoresist	3526	L16

*DB-DWPI; PLUR YES; OP OR*

L15	l13 and (l14 or poly\$)	0	L15
L14	low near3 (k or dielectric\$)	7611	L14
L13	L12 and l11 and l10 and l9	6	L13
L12	n2 or nitrogen or ar or argon or he or helium or ne or neon or kr or krypton or inert near3 gas\$ or xe or xenon	1255698	L12
L11	etch\$ or patern\$ or pattern\$ or remov\$	1243038	L11
L10	hard near3 mask?	58	L10
L9	resist or photoresist	84478	L9

*DB USPT,PGPB; PLUR=YES; OP OR*

L8	l5 same (l6 or poly\$)	0	L8
L7	L5 and (l6 or polymer\$)	5	L7
L6	low near3 (k or dielectric\$)	24819	L6
L5	L4 same l3 same l2 same l1	9	L5
L4	n2 or nitrogen or ar or argon or he or helium or ne or neon or kr or krypton or inert near3 gas\$ or xe or xenon	767000	L4
L3	etch\$ or patern\$ or pattern\$ or remov\$	1982651	L3
L2	hard near3 mask?	384	L2
L1	resist or photoresist	213659	L1

END OF SEARCH HISTORY